

**PATENT APPLICATION**

**RESPONSE UNDER 37 CFR §1.116  
EXPEDITED PROCEDURE  
TECHNOLOGY CENTER ART UNIT 1714**

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re the Application of

Toru YAMADA

Group Art Unit: 1714

Application No.: 10/582,802

Examiner: G. RAO

Filed: June 14, 2006

Docket No.: 136170

For: VAPOR PHASE GROWTH APPARATUS AND METHOD OF FABRICATING  
EPITAXIAL WAFER

**AMENDMENT AFTER FINAL REJECTION UNDER 37 CFR §1.116**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

In reply to the January 24, 2011 Office Action, please consider the following:

**Amendments to the Claims** as reflected in the listing of claims; and

**Remarks.**